



## Tool Configuration / Specifications

Process Chamber 2,3& 4	Deposition Ring	0040-75531	Deposition Ring PVD Tungsten
Process Chamber 2,3& 4	DC Power Supply	0190-26736	ENI 0190-26736 (Optima 1.5)
Process Chamber 2,3& 4	Gauge	3310-00075	Analog, Hot Ion/Combi High vacuum, 2.75
Process Chamber 2,3& 4	Gauge	3310-00074	Capacitance Diaphragm, 1.33
Base System	Cool down Chb. A& B		Pass Through Chambers with cool down
Base System	Degas Chb E&F		Dual Mode Degas Chambers
DMD Chamber	Isolation Valve	3870-01805	Valve Pneumatic Rating 2-3/4CF NW 40XNW40 24VDC AIR-CONT
DMD Chamber	Vacuum Gauge	0190-23645	Specifications for MPG401 Magnetron Pirani Gage w/ cable
DMD Chamber	Fitting	3300-05653	Fitting TBG Union 1/4" Tee
DMD Chamber	Fitting adaptor	3300-03799	Fitting Adaptor 1/8 x 1/4"
Degas Chb E&F	Heater		Lamp Halogen 120V
Degas Chb E&F	Valve		Manual Valve for RGA
Remote Options	EMO		Turn-to-Release button
Remote Options	Safety labels.		English
Remote Options	Cryo compressor	0190-19395	Capable of supporting five(5) cryo pumps per compressor
Remote Options	Support Equip Lines		Cryo He Lines = 75 ft, LC to Cryo/heat exchanger =50 ft
Remote Options	Cables		Umbilical from MF to Equipment Rack 75-foot remote components
Remote Options	Heat exchanger		Daikin
Facilities Options	Detectors		System water leak and smoke detectors.
Base System	Cryo Pumps 1Transfer and 1Buff	0190-25016	CTI On Board supplied by the OEM.
Facilities Options	Cryo pumps Chambers E, F, 2,3 &4	0190-25015	CTI On Board supplied by the OEM.
Monitors	System Monitor		Through wall for WZ 25 ft cable
Monitors	Add Monitor w/Keyboard		Additional Monitor w/Keyboard UZ 25 ft cable

Browse our site at [www.moov.co](http://www.moov.co)

The information contained in this data sheet is, to our knowledge, accurate. We do not warrant the completeness or accuracy of the information contained herein. Any offer by you to purchase the equipment described in this data sheet shall be subject to the terms and conditions of sale.